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Pages: 226 - 231

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## 3 A highly flexible design and production framework for modularized microelectromechanical systems

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## 4 Test structures for determining design rules for microelectromechar based sensors and actuators

Zincke, C.; Gaitan, M.; Zaghloul, M.E.; Linholm, L.W.; Microelectronic Test Structures, 1994. ICMTS 1994. Proceedings of the 1994 International Conference on , 22-25 March 1994 Pages:44 - 50

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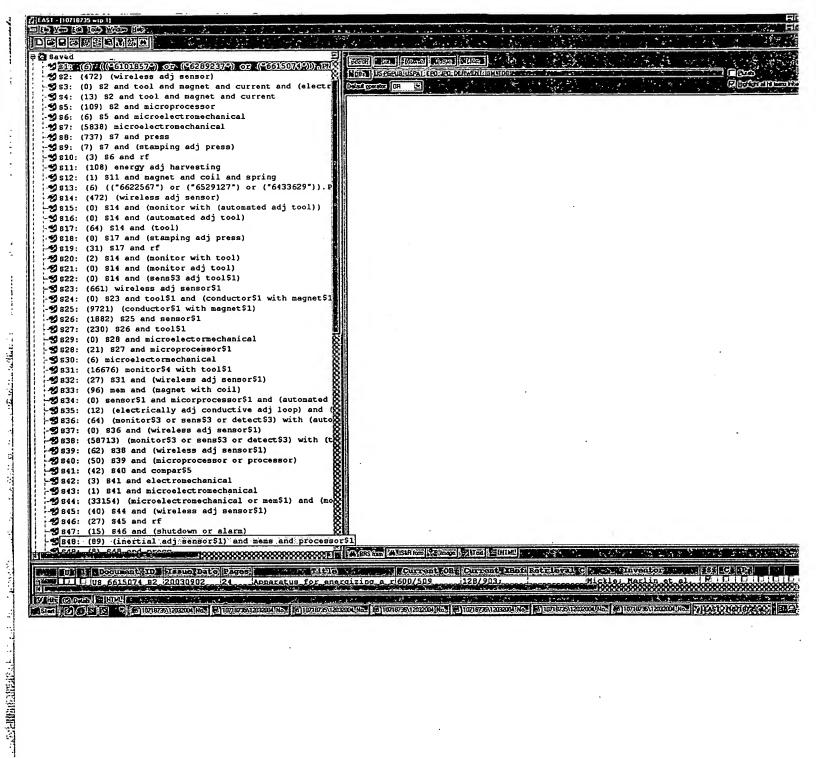
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